PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Oh et al. Group Art Unit: 1795

Serial No.: 10/615,842 Examiner: Phasge, Arun S.

Filed: July 10, 2003 Docket No.: 421/170/8/2 CIP

Confirmation No.: 9995

For: DEPOSITION METHOD FOR NANOSTRUCTURE MATERIALS

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COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicant's positions on the issues appear in the responses. The Statement of Reasons for Allowance should not be used to interpret the cited claims, particularly to the extent if any that the Examiner's Statement may differ from the express language of the claims and/or Applicant's positions on patentability of those claims.

It is respectfully submitted that the allowed claims should be entitled the broadest reasonable interpretation and broadest range of equivalents that are appropriate in light of the language of the claims, the supporting disclosure and Applicant's prosecution of the claims, without reference to the Statement of Reasons for Allowance.

Respectfully submitted,

JENKINS, WILSON, TAYLOR & HUNT, P.A.

Date: September 25, 2008

By: <u>S/Aナー</u> Jeffréy L. Wilson

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